

# ELECTRONIC GAS

## PLASMA ETCHING MIXTURE O<sub>2</sub>/CF<sub>4</sub>

Carbon Tetrafluoride can be mixed with oxygen in order to provide concentration of less than 100%. Using Carbon Tetrafluoride in this form is used for plasma cleaning of CVD reactors. Carbon Tetrafluoride / oxygen mixtures are prepared as ordered. Concentrations other than those listed below are available upon request.

### Container Information

**CYLINDER CONNECTION:** std: CGA-880 (O<sub>2</sub> < 5%) / CGA-590 (O<sub>2</sub> > 5%)

**DOPING CONCENTRATIONS** can be mixed with UHP or VLSI grade balance gases

Oxygen Concentration	Cylinder Size	Pressure psig @ 70°F	Content	
			ft <sup>3</sup>	m <sup>3</sup>
4%	044	500	61.5	1.74
	016	500	24	0.68
8.5%	044	500	62	1.74
	LFE-DE-100 016	500	24	0.68
17.5%	044	500	62	1.74
	LFE-DE-100 016	500	24	0.68
92%	044	500	60	1.57
	LFE-DE-180 016	500	22	0.60
97%	044	500	60	1.57
	LFE-DE-180 016	500	22	0.60
<b>SHELF LIFE: 1 year</b>				

### DOT Shipping Information

#### CARBON TETRAFLUORIDE BALANCE

Oxygen Conc	Shipping Name	Shipping Papers	Shipping Labels
4%	4% Oxygen/Carbon Tetrafluoride Mixture	Compressed Gases, Non-flammable, nos (4% Oxygen/Carbon Tetrafluoride Mixture) 2.2 UN 1956	Non-flammable Gas
8%	8% Oxygen/Carbon Tetrafluoride Mixture	Compressed Gases, Non-flammable, nos (8% Oxygen/Carbon Tetrafluoride Mixture) 2.2 UN 1956	Non-flammable Gas
10%	10% Oxygen/Carbon Tetrafluoride Mixture	Compressed Gases, Non-flammable, nos (10% Oxygen/Carbon Tetrafluoride Mixture) 2.2 UN 1956	Non-flammable Gas
20%	20% Oxygen/Carbon Tetrafluoride Mixture	Compressed Gases, Non-flammable, nos (20% Oxygen/Carbon Tetrafluoride Mixture) 2.2 UN 1956	Non-flammable Gas